

Title (en)

METHOD AND DEVICE FOR VENTING A VACUUM CHAMBER

Title (de)

VERFAHREN UND VORRICHTUNG ZUM FLUTEN EINER VAKUUMKAMMER

Title (fr)

PROCÉDÉ ET DISPOSITIF D'ADMISSION POUR UNE CHAMBRE À VIDE

Publication

EP 2960520 A1 20151230 (DE)

Application

EP 15174043 A 20150626

Priority

DE 102014109005 A 20140626

Abstract (en)

[origin: JP2016008612A] PROBLEM TO BE SOLVED: To provide a method and apparatus capable of performing a fast pouring of gas into a vacuum chamber without being hindered by a rotor of a vacuum pump connected to the vacuum chamber still being rotated even though already been shut off that can be attained as easily as possible even under a relative large volume of the vacuum chamber.SOLUTION: This invention relates to a method for feeding air into a vacuum chamber 14 connected to a vacuum pump 12, in particular, a turbo molecular pump in which gas is also fed to the vacuum pump (12) including one rotor and one stator in simultaneous with feeding of gas into the vacuum chamber 14, the gas feeding operation is carried out just after each of the pump rotors is shut off and a rate of feeding gas is increased during each of the gas feeding processes just after the pressure at the vacuum pump 12 reaches a pre-settable limit value.

Abstract (de)

Ein Verfahren zum Fluten einer mit einer Vakuumpumpe, insbesondere Turbomolekularpumpe, verbundenen Vakuumkammer, bei dem mit dem Fluten der Vakuumkammer gleichzeitig auch die einen Rotor sowie einen Stator umfassende Vakuumpumpe geflutet wird, zeichnet sich dadurch aus, dass das Fluten unmittelbar nach einem jeweiligen Abschalten des Pumpenrotors erfolgt und die Flutrate während eines jeweiligen Flutvorgangs erhöht wird, sobald der Druck in der Vakuumpumpe einen vorgebbaren Grenzwert erreicht hat. Es wird auch eine geeignete Vorrichtung zur Durchführung des Verfahrens angegeben.

IPC 8 full level

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CPC (source: EP)

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Citation (applicant)

EP 1739308 B1 20080618 - VARIAN SPA [IT]

Citation (search report)

- [X] JP H018714 Y2 19890308
- [A] EP 2053249 A2 20090429 - PFEIFFER VACUUM GMBH [DE]

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Designated contracting state (EPC)

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